UNIT IV

1.Which o	one the following is not a componer	t of smart sensor?
a) Power s		ocomputer
c) DAC	d) Diaph	ragm
a) Micro eb) Micro ec) Mini ele	stands for the following abbreviation electrical mechanical electro mechanical system electro mechanical electrical mechanical system system	n
a) Beb) Sla	elt conveyors transport materials lat conveyors requires high maintena	nnce
c) Vi	ibrating conveyor can convey mater	ials of any friction factor
 4.Screw conveyors usually handle lightweight materials Today almost all electronic weighing scales usefor the measurement of weight. a) Magneto resistance b) Strain guage c) Load cell d) Gyroscope 		
5.In a lor	ongitudinal field,changes in magneti	zation due to torsion given in a ferromagnetic rod is
a.	Hall effect	
b.	. Matteucci effect	
c.	Villari effect	
d.	Thomson effect	
a. b. c.	ange of the magnetization of a mater Hall effect Matteucci effect Villari effect Wiedemann effect	ial when subjected to a mechanical stress is called
	a longitudinal magnetic field	n which an electric current is flowing when the rod is
b.	Matteucci effect	
c.	Villari effect	
d.	. Wiedemann effect	
8.A	sensor uses the fact that	the electrical resistance in a ferromagnetic thin film
	hanged through an external magnetic	_
a.	Thermoemf sensor	

- b. Inductive sensorc. Magnetoresistive sensord. Magnetostriction sensor
- 1. The 'eddy current' forces the current flowing through the interior of a material to move to its surface level is referred to as
 - a. Skin effect
 - b. Matteucci effect
 - c. Villari effect
 - d. Wiedemann effect
- 2. SQUID refers to
 - a. sensitive magnetometer used to measure extremely subtle magnetic fields
 - b. sensitive magnetometer used to measure extremely crude magnetic fields
 - c. sensitive magnetometer used to measure crude magnetic fields
 - d. sensitive magnetometer used to measure subtle magnetic fields
- 3. _____is a property of ferromagnetic materials that causes them to change their shape when subjected to a magnetic field.
 - a. Magnetoresistive sensor
 - b. Magnetization
 - c. Magnetostriction
 - d. Pyroelectric
- 4. ______is a mechanical property that denotes the elasticity in tension or compression.
 - a. Magnetization
 - b. Δy effect
 - c. Villari effect
 - d. Wiedemann effect
- 5. _____ which is basically a change in resistance of specified materials with magnetic field impressed.
 - a. Thomson effect
 - b. Matteucci effect
 - c. Villari effect
 - d. Wiedemann effect
- 6. The output voltage of a Hall sensor is directly proportional to the
 - a. Electric field
 - b. Magnetic field
 - c. Total moment
 - d. Total Flux
- 7. Tiny devices that use variations in an external magnetic field to generate electrical signals and energy
 - a. Wiegand and pulse wire sensors
 - b. Thermal sensor
 - c. Magnetic sensor
 - d. Inductive sensor
- 8. SQUID means

a	. Superior Quantum Interference Devices
t	o. Super Quantum Interference Devices
C	2. Superconducting Quantum Indicating Devices
Ċ	I. Superconducting Quantum Interference Devices
9. The	e ability of two weakly coupled superconductors to sustain at zero voltage, a super current is
	ociated whose magnitude depends on the phase difference between the two superconductors
	ralled
а	. Hall effect
ŀ	o. Josephson effect
	v. Villari effect
Ċ	I. Wiedemann effect
10. Th	e maximum current which Josephson weak link can support without developing any voltage
acr	oss it is known as
а	. Josephson effect
t	o. Villari effect
C	. Wiedemann effect
Ċ	l. Critical current
11	arise because of Lorentz force on the charge carrier transport phenomena in
cor	ndensed medium.
a	. Galvanomagnetic effects
	Josephson effect
C	. Villari effect
d	l. Wiedemann effect
	is a mechanical property that measures the tensile or
cor	mpressive stiffness of a solid material when the force is applied lengthwise.
а	. Elasticity
k	o. Young's modulus
	e. Solidity
C	I. Tensile modulus
	lari effect is also called as
	. Mateucci effect
	o. Josephson effect
	inverse magnetostrictive effect
C	I. Wiedemann effect
	External magnetic field is applied to ferromagnetic material in vertical direction, the dipoles
_	s arranged in
	same direction
	o. in different direction
	. horizontal direction
C	I. transverse direction
15. A _	sensor is an electronic device that is designed to monitor, detect, record and
reg	ulate linear and rotational forces exerted upon it.

a. Radiationb. Magnetic

	force torque Inductive
16. Pack	ed in a small package with low power consumption, this sensor allows for
	nuous distance reading.
	Thermal sensor
b.	Magnetic sensor
	Inductive sensor
d.	IR proximity sensor
17 Prov	imity sensor operate over a range of
	10cm to 80cm
	20cm to 90cm
	30cm to 60cm
	1m-2m
10 A	
-	ecific type of material when subjected to pulse voltages under stress shows switching t is called
	Sixtus-Tonks effect
	Magnetic sensor
	Inductive sensor
	IR proximity sensor
	n exposed to an alternating external magnetic field, a Wiegand wire will initially retaining
	agnetic polarity - when the external field reaches a certain threshold, the polarity of the
	segment will
	Be same
	Reverse
	abruptly Reverse
a.	adverse
_	gand sensors
	Has self-powering capacity
	Does not have self powering capacity
	Takes power from another source
d.	None of the above
21. SQU	IDs are sensitive enough to measure fields as low as
a.	$6 \times 10^{-14} \mathrm{T}$
b.	$5 \times 10^{-14} \text{ T}$
c.	$7 \times 10^{-14} \mathrm{T}$
d.	$4 \times 10^{-14} \text{ T}$
22. Whe	n certain materials are cooled below a temperature remarkable
	actions of electric currents and magnetic field occur.
	Certain
	Superconducting transition
	Curie
	Critical
23. In so	lid or hollow cylindrical shaft, stress develops in two principal orthogonal directions, one

compressive and other tensile, each at angle _____

	b.	±45°
	c.	±120
	d.	$\pm65^{\circ}$
24.	Lore	ntz force is
	a.	F=eE+e[vxB]
	b.	F=eE+v[exB]
		F=ev+e[vxB]
		F=vE+e[vxB]
		1 12 14[112]
25	Hall	mobility is the product of
	a.	drift mobility of the carrier and hall scattering factor
		drift mobility of the carrier and scintillation factor
		Brownian movement and hall scattering effect
	u.	Scattering and drift mobility
36	A C -	
20.		ensor is a
		Subsystem
		Machine Madula
		Module All the above
	a.	All the above
27	The t	function of a sensor is to
۷1.	a.	
		Separate physical parameters
		Track and transfer data to computer processor
		Both a and c
	u.	Dom a and C
28	Whic	ch of the following are examples of sensors?
_0.	a.	TD
	b.	MARG sensor
		Biosensor
		All the above
29.	Sens	or provides output signal depending on
	a.	Input
	b.	Physical quantity
	c.	Both a and b
	d.	None of the above
30.		ors convert signals from analog to domain.
		Digital
		Electrical
		Mechanical
	d.	Both a and b
31.		sensor is abbreviated as
		Light Dependent Resistor
	b.	Luminous Duplicated Resistor

c. None of the above

a. ±60°

32. Wh	ich sensors resistance value varies with respect to light intensity?
	Photosensitive
	Bio
c.	All the above
33. LD	R sensor is made up of material.
a.	Conductors
b.	Insulators
c.	Semiconductor
d.	None of the above
34. Wha	at is the resistance value of the LDR sensor in absence of light
a.	Several mega ohms
b.	100's of megaohms
c.	10-100ohms
d.	10,0000 ohms
35. The	ratio between the resultant output signal to a measured property of a sensor is called
a.	Sensitivity
b.	Resistivity
c.	Conductivity
d.	Both b and c
	sensor provides data about the chemical composition of its environment in terms of
	and liquid phase.
	Chemical sensor
	Liquid sensor
	Air sensor
d.	All the above
37. Ana	log sensors generate analog kind of output signals.
a.	Discrete
b.	Continuous
c.	Both a and b
d.	Does not generate
38. Whi	ich of the following is the function of the accelerometer sensor?
	Detects changes in position, orientation
	Detects variation in velocity, shock
	Detects variation in tilt and vibration
d.	All the above
39. Ana	alog accelerometers are classified based on
	Sensitivity
	Configuration
	Both a and b
	Power dissipation
40.	sensors detect a quantity of light striking the sensor component.
	Light sensor
	Beam sensor
	Velocity sensor
	Speed sensor

41. _____ is used as a switch in Analog sensors.

	b.	LDR PN diode
		Thyristor All the above
42.	a. b. c.	EM induction Electric induction Magnetic induction All the above
43.	a. b. c.	Sure sensor generates output in form. Digital Analog Both a and b Heat
44.	a. b. c.	output generated by the piezoelectric sensor is Mechanical Electric charge Chemical All the above
45.	a. b.	ligital sensors overcome the disadvantages of analog sensors? Yes No Maybe
46.	a. b. c.	ch of the following are the components of a digital sensor? Cable Transmitter Sensor All the above
47.	a. b. c.	ography process is used to pattern: Metal and semiconductor layers Metal and insulating layers Metal, Semiconductor and insulation layers Semiconductor and insulation layers
48.	a. b. c.	are commercially available silicon wafers circular in shape? For fabricating maximum number of devices per unit area For ease of handling during process flow execution Because the ingot from which it is derived is cylindrical owing to upstream processes Making flats to identify the silicon type is easier on circular wafer
49.	a.	romachining process is used to increase selectivity, accuracy, performance etc., True False
50.	a.	rmal deformation is the major problem in micromachining True False

51. Interest of increasing wafer diameter from 200 mm to 300 mm

- a. The price of a 300 mm wafer is lower
- b. It is easier to fabricate
- c. To produce more silicon devices from a single wafer
- d. To increase the size of a die
- 52. What is a n type Si semiconductor (SC)
 - a. A Si semiconductor without impurities
 - b. A Si Semiconductor with impurities from column III and V of Mendeleev table
 - c. A Si Semiconductor with impurities from column III of Mendeleev table
 - d. A Si Semiconductor with impurities from column V of Mendeleev table
- 53. What is the thickness of the dielectric in a 28 nm MOS transistor
 - a. Lower than 1 µm
 - b. Lower than 10 nm
 - c. Lower than 1 nm
 - d. Lower than 0.1 nm
- 54. The graphene-based sensors are normally highly sensitive for individual gas molecule detection, ...
 - a. because of linear energy dispersion and low density of states near the Dirac point
 - b. because that the molecules are absorbed on a uniform single atomic sheet
 - c. because of interaction with π electrons
 - d. because of high conductance in grapheme
- 55. In a nanobiosensor based on a cantilever used in dynamic mode, the shift of the resonance frequency is due to:
 - a. A variation of absorbed mass
 - b. A variation of temperature
 - c. A variation of stress
 - d. A piezoelectric effect
- 56. A nano biosensor made of?
 - a. A probe and a surface
 - b. A sensing layer and a transducer
 - c. A target and a probe molecule
 - d. A biomarker and a probe
- 57. The quantities cannot be measured by a load cell is....
 - a. Pressure
 - b. Temperature
 - c. Level
 - d. All of the above
- 58. A load cell is a
 - a. Strain gauge
 - b. Photovoltaic cell
 - c. Thermistor
 - d. Pressure picks up
- 59. A cadmium sulfide cell is a
 - a. Solar cell
 - b. Dry cell
 - c. Photovoltaic cell
 - d. Photoconductive cell
- 60. What is a conveyor?

- a. A conveyor is a static equipment that is used to store heavy and bulky materials
- b. A conveyor is a moving equipment that is used to store heavy and bulky materials
- c. A conveyor is a moving equipment that is used to carry heavy and bulky materials
- d. A conveyor is a moving equipment that is used to carry light and compact materials only
- 61. Which of the following is true about the speed of the conveyor belt?
 - a. Fixed conveyors need not be shut down during any speed change
 - b. Adjustable speed belts can be changed only manually
 - c. Fixed speed drives can undergo minor speed changes
 - d. Variations of speed is not possible with conveyors
- 62. Which of the following is not of importance when a conveyor is designed?
 - a. Type of industry where the conveyor is being used
 - b. Type of material being carried by the conveyor
 - c. Cost
 - d. Length of travel of the conveyor
- 63. Which of the following is true about frame configuration?
 - a. Frame configuration refers to the size of the conveyor
 - b. Frame configuration refers to the size and shape of the conveyor
 - c. Frame configuration refers to the capacity of the conveyor
 - d. Frame configuration refers to the shape of the conveyor
- 64. Which of the following is a correct description about the different types of conveyors?
 - a. Belt conveyor transports material in any direction
 - b. Slat conveyor requires high maintenance
 - c. Vibrating conveyor can convey materials of any friction factor
 - d. Screw conveyors usually handle lightweight materials
- 65. Which of the following is true about frame configuration?
 - a. Frame configuration refers to the size of the conveyor
 - b. Frame configuration refers to the size and shape of the conveyor
 - c. Frame configuration refers to the capacity of the conveyor
 - d. Frame configuration refers to the shape of the conveyor
- 66. Choose the correct unit of throughput (Throughput is a measure of the capacity of the conveyor tohandle bulky materials).
 - a. Cubic feet per minute
 - b. Meter cube
 - c. Square feet per second
 - d. Meter square
- 67. Which of the following is false about conveying systems?
 - a. An essential factor to consider before choosing the right conveyor system is the environment of operation
 - b. Conveyors cannot be used as feeders
 - c. The composition of the material being conveyed is very important
 - d. The surrounding temperature is one of the deciding factors
- 68. Which of the following is false about conveyors?
 - a. Cleats can be used to prevent slipping
 - b. Backstopping brakes are used for straight belts
 - c. Anti-static belts are used when electric components are conveyed
 - d. Soft starters avoid overloading the motor
- 69. Sensors that use an additional energy source for their operation are called......
 - a. modulating sensors

- b. Interrogating sensors
- c. Direct sensors
- d. Both a) and b)
- 70.sensors are not affected by ambient conditions, such as dust, humidity and vibrations and are insensitive to some ambient conditions based on the principle that these sensors display a constant flow of electrical current, making their characteristics constant over time.
 - a. A LVDT
 - b. LVDT
 - c. Hall effect
 - d. Load cell
- 71. The maximum amount a weight reading may deviate from a straight line between zero and themaximum capacity of the balance is:
 - a. Repeatability
 - b. Capacity
 - c. Linearity
 - d. Net weight
- 72. The smallest increment of weight a balance will display:
 - a. Tare weight
 - b. Readability
 - c. Net weight
 - d. Capacity
- 73. A hook or connection point on the bottom of the balance that suspends items for weighing
 - a. Auto zero tracking
 - b. Full-scale tare
 - c. Calibration mass
 - d. Below-balance weighing
- 74. Capability that lets users tare via computer or manually
 - a. Checkweighing
 - b. Digital tare
 - c. Net weight
 - d. Digital filters
- 75. Weighing application that uses a preset reference weight to equal 100%
 - a. Percent weighing
 - b. Keypad calibration
 - c. Net total formulation
 - d. Checkweighing
- 76. Strain gage load cells provide accuracies from within
 - a. 0.03% to 0.25% full scale
 - b. 0.3% to 2.5% full scale
 - c. 3% to 5% full scale
 - d. 3% to 4% full scale
- 77. Gauge Factor is defined as the ratio between
 - a. the unit change in resistance to the per unit change in length.
 - b. the unit change in resistance to the per unit change in area.
 - c. the unit change in resistance to the per unit change in resistivity.
 - d. the unit change in resistance to the per unit change in temperature.
- 78. Hydraulic load cells are -----least accurate, lease sensitive and capacitance load cells are ----

a. least accurate, highly accurate

- b. most accurate, highly accurate
- c. moderately accurate, highly accurate
- d. least accurate, less accurate

Part -B (4 marks)

- 1. Compare MEMS sensors and Nano Sensors
- 2. List the advantages of MEMS.
- 3. Identify the important features of smart sensors.
- 4. What is Hall effect transducer?
- 5. Discuss the operation of magneto elastic sensor.
- 6. Define weimann effect
- 7. Compare microelectronics and microsystems.
- 8. Explain Micromachining.
- 9. Define hall effect.
- 10. Define villari effect.

Part-C (12 marks)

- 1. Describe the role of MEMS in instrumentation.
- 2. Explain Hydraulic and pneumatic load cell with neat diagram
- 3. Explain Electrical type load cell with neat diagram
- 4. What is meant by thick film and thin film technology? Explain.
- 5. Explain with a neat block diagram the construction, operation and important characteristics of a smart sensor.
- 6. Explain Galvanomagnetic effect sensor
- 7. Discuss the operation of magneto elastic sensor.
- 8. Explain the different designs of weighing systems.
- 9. Explain about weigh feeder type.